



International Academy, Research, and Industry Association

Best Paper Award

Key Parameter Identification for Faulty Wafer
Detection Using Image Processing

By

Shu-Kai S. Fan, Du-Ming Tsai, Chih-Hung Jen, Rui-Yu Huang, Kuan-Lung Chen

Presented during ICAS 2018, The Fourteenth International Conference on Autonomic and Autonomous Systems,
held in Nice, France during May 20 - 24, 2018.

IARIA Board

